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Recent Advances on Substrate Integrated Waveguide Filters:  
Simulations, Technologies and Performances

# Millimeter-Wave Substrate-Integrated Circuits on Photo-imageable Substrate and LTCC

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## OUTLINE

Photoimageable thick film technology

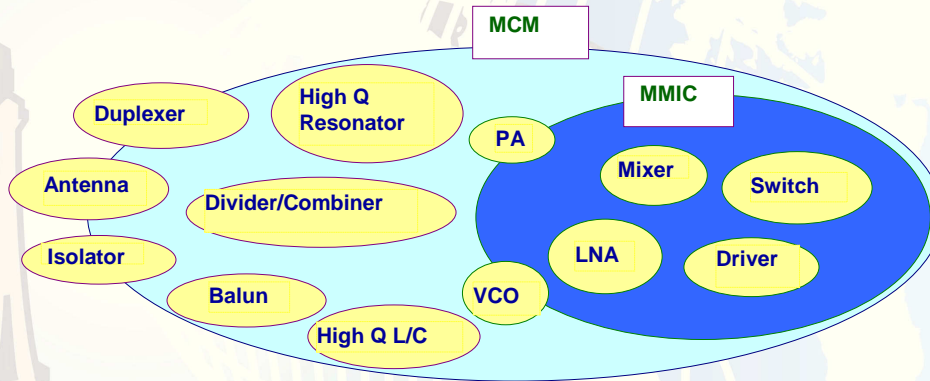
“Rapid Prototyping” LTCC Technology using LPKF Laser

Laser Machining of Microvias and Trenches

Future Work:-

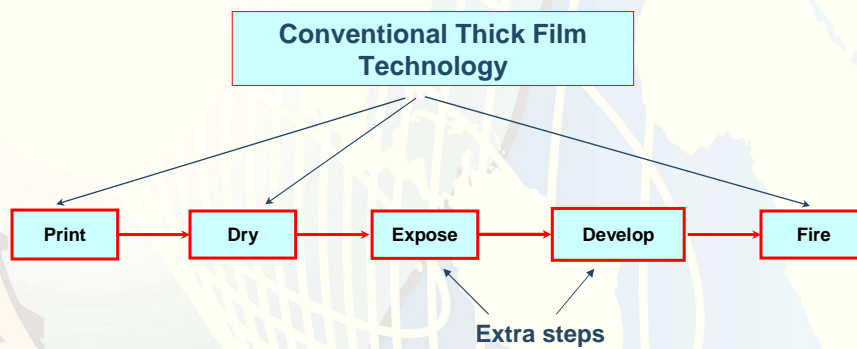
- Novel filter topologies
- SIWs & Antennas
- Systems integration

## MOTIVATION



THICK-FILM TECHNOLOGY PURSUED FOR LOW COST FABRICATION OF LARGE AREA SYSTEM-ON-SUBSTRATE APPLICATION

## MULTILAYER PHOTOIMAGEABLE THICK FILM PROCESS



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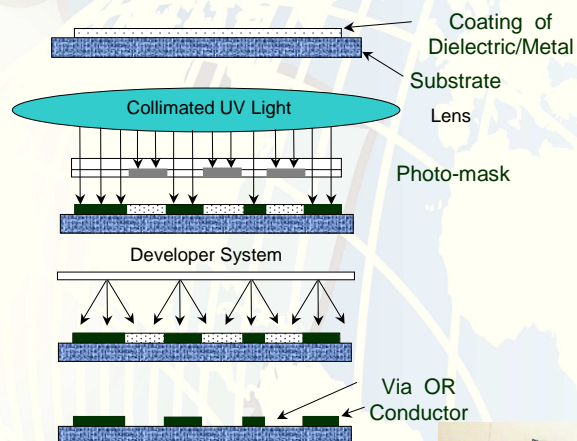
- Special type of photosensitive thick film material
- Features are defined by exposure of dry paste to UV light
- Gold, silver and dielectric pastes available
- Rheology of paste can be optimised for smooth finish
- Fine width/gap, easy to fabricate, low cost

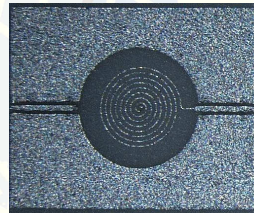
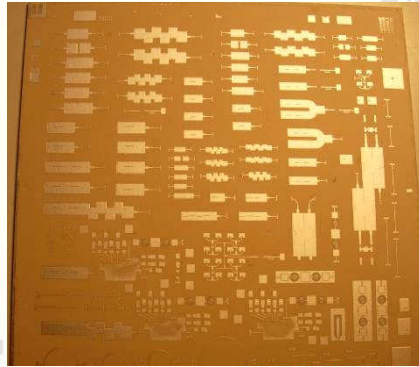
Screen Printing/  
Dry at 80°C

Exposure

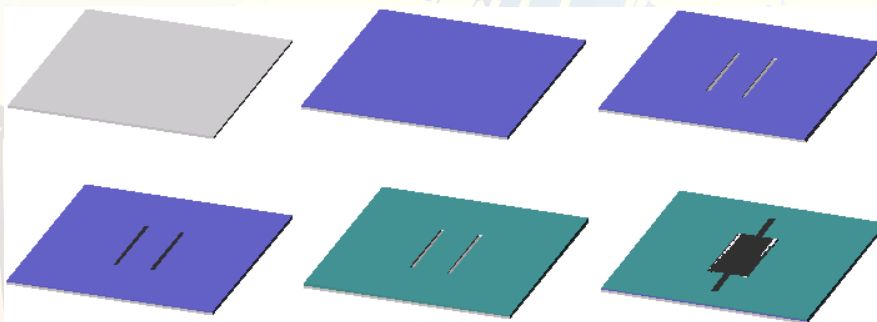
Development  
0.1% MAE

Firing



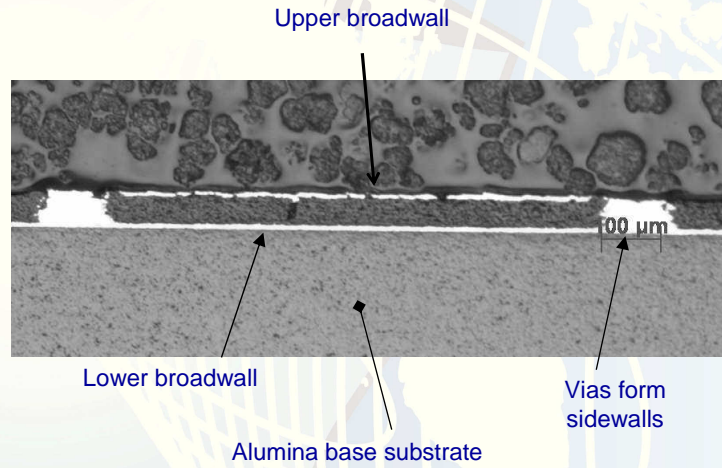


## SIW Fabrication

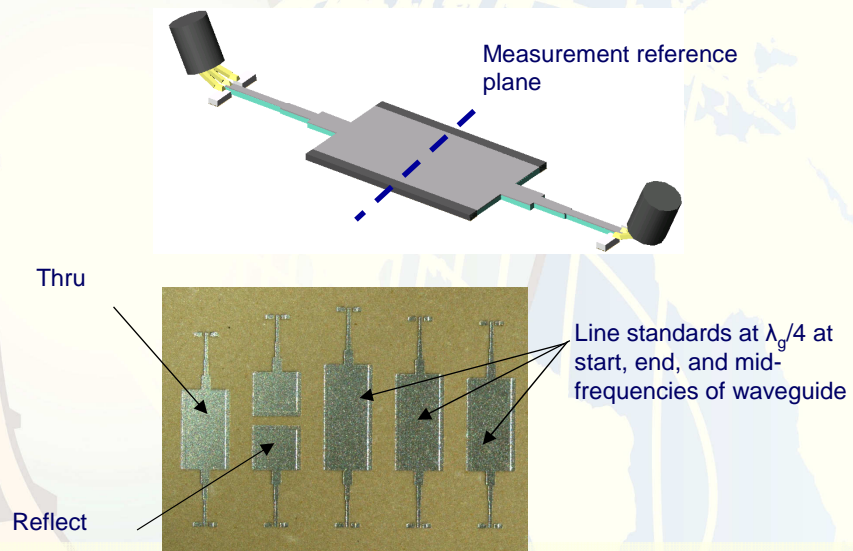


- Conductor print defines ground plane
- Dielectric layer exposed & developed to create vias for sidewalls
- Conductor print forms guide sidewalls
- Repeat dielectric prints to build guide height
- Final conductor print forms upper broadwall

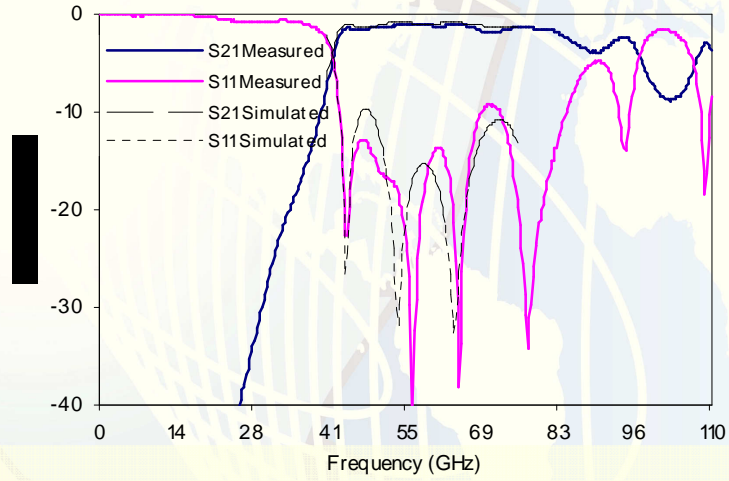
## Fabricated waveguide



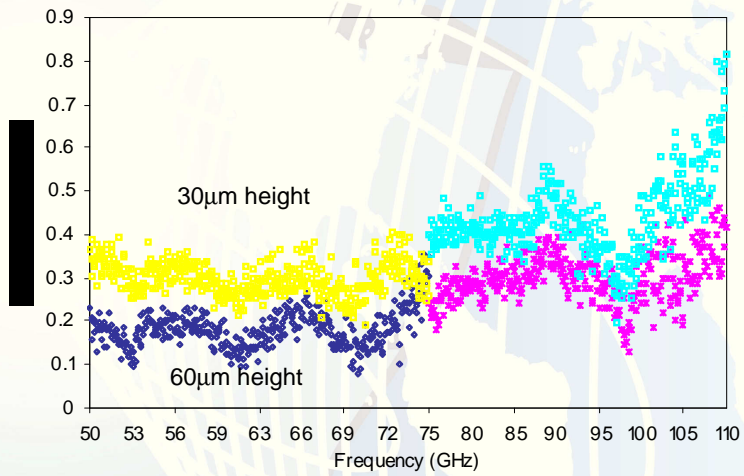
## TRL calibration



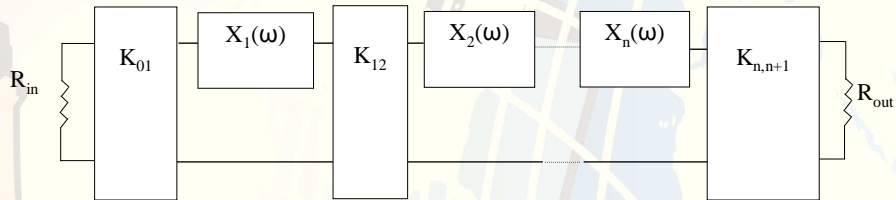
### V band waveguide back-to-back transition measurements



### Measured attenuation (dB/mm) for V and W-band waveguides.

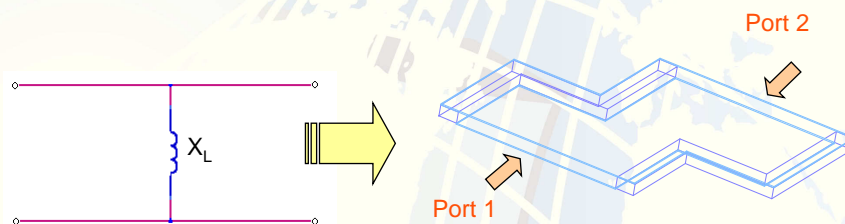


## Inverter-coupled filter



- $K_{ij}$  impedance inverters and  $X_n(\omega)$  resonator sections are series connected

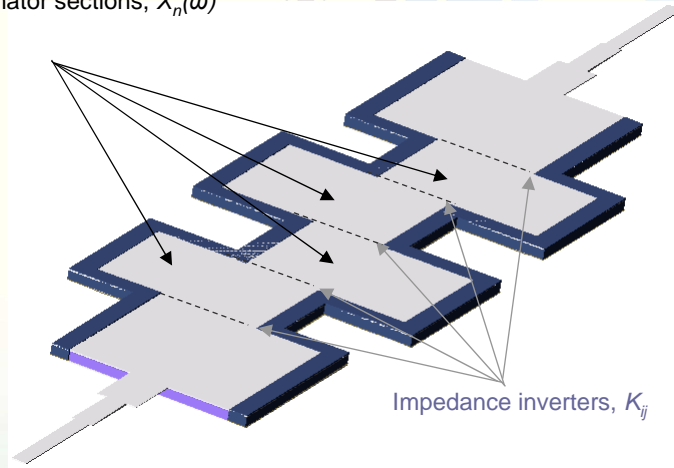
## Inverter



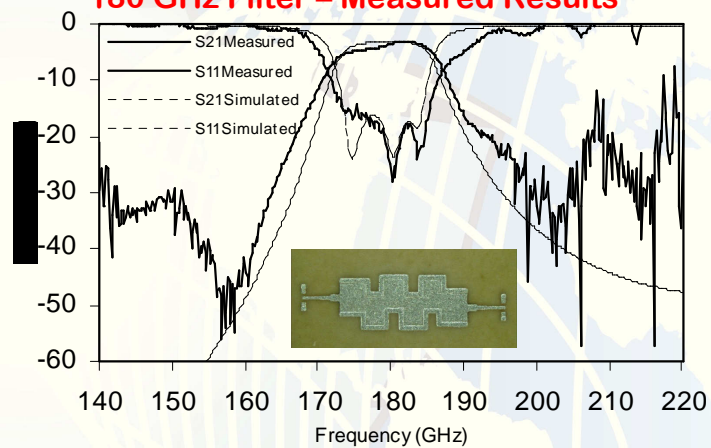
- Inductive reactance readily realized by a H-plane offset
- Displaced junction characterized in HFSS

## SIW filter synthesized

Resonator sections,  $X_n(\omega)$



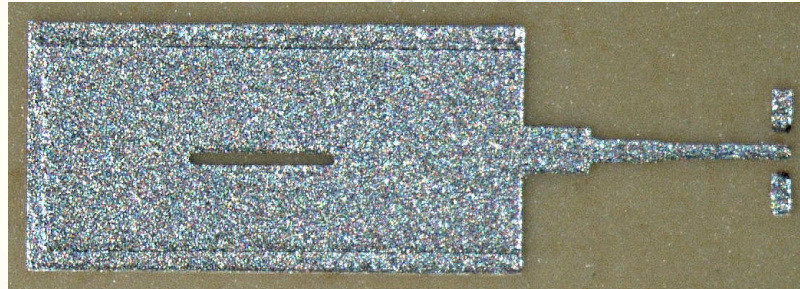
## 180 GHz Filter – Measured Results



Stephens, D.; Young, P.R.; Robertson, I.D., "Design and characterization of 180 GHz filters in photoimageable thick-film technology" IEEE MTT-S IMS, 2005, vol. 1, pp. 451-454

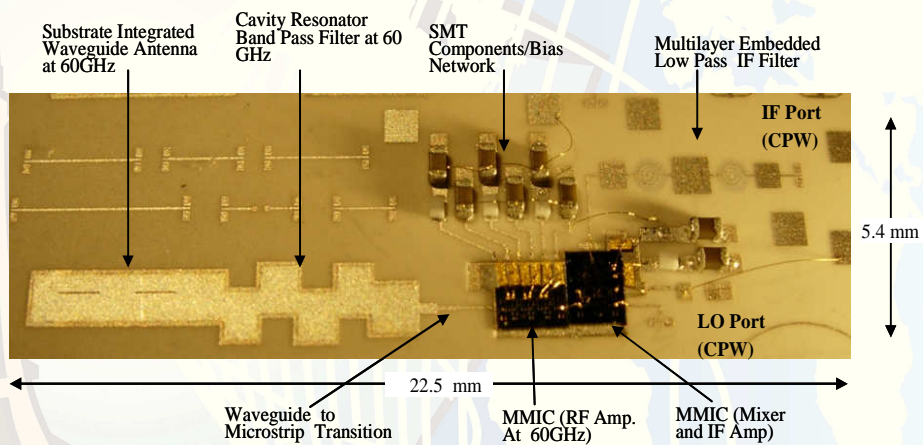


### W-band Antenna



Stephens, D.; Young, P.R.; Robertson, I.D. (2005) **W-band substrate integrated waveguide slot antenna**. Electronics Letters, 41(4), pp.165-167.

### Complete SIW/MMIC 60GHz Receiver



## Major drawback of thick film photoimageable approach for SIWs

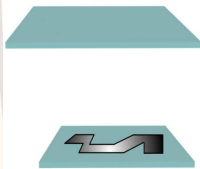
**Waveguide height!**

**Even achieving 100 microns height requires many print-expose-fire cycles**

**Alignment becomes challenging**

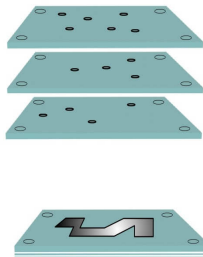
## LTCC Process

**Pre-Conditioning**



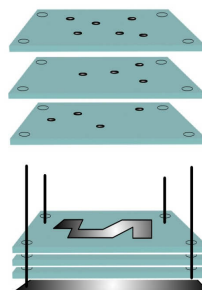
**Cutting & Firing**

**Via machining**



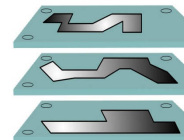
**Laminating**

**Via filling**

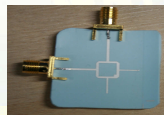
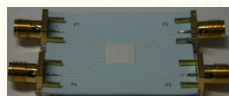
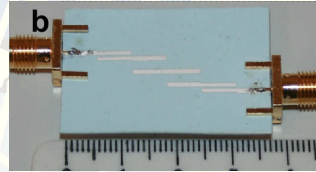


**Stacking**

**Screen printing**

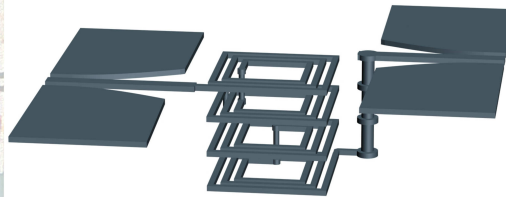
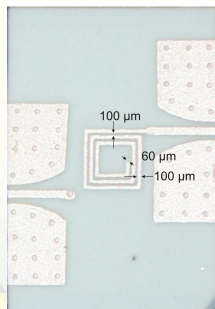
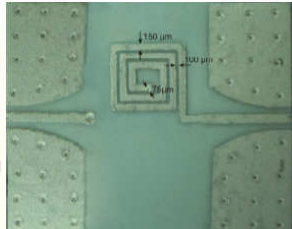


## LTCC prototyping using LPKF laser system



## Equipment and Material

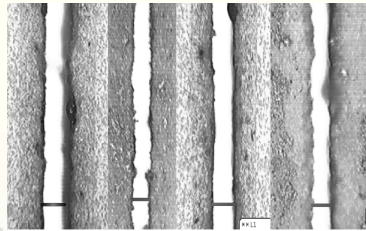
- Protolaser 200 Nd:Yag Laser etching machine from LPKF
- 943PX, 254  $\mu\text{m}$  green tape from DuPont
- HF612 silver paste from DuPont
- HF600 via filling paste from DuPont



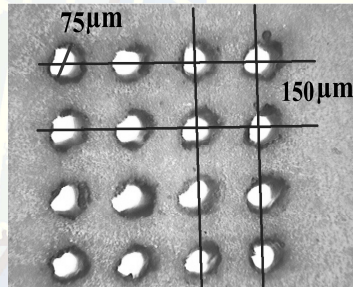
## Via machining

Mechanical drill and punches	Laser machining
Low capital cost	High capital cost
Single use	Multipurpose
Low punching rate	High punching rate
Clean and precise diameter	Not very clean, precision suffers
Holes only	Arbitrary shape possible
No optimization required	Hard to optimize
Direct contact with the material	No direct contact with material
Short tool life	Long life

## Minimum dimensions

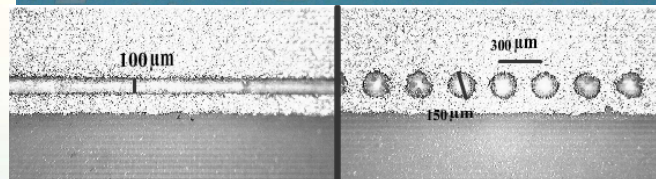
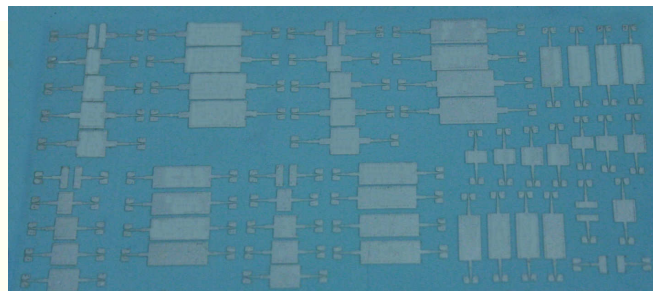


76 $\mu\text{m}$  67 $\mu\text{m}$  59 $\mu\text{m}$  46 $\mu\text{m}$

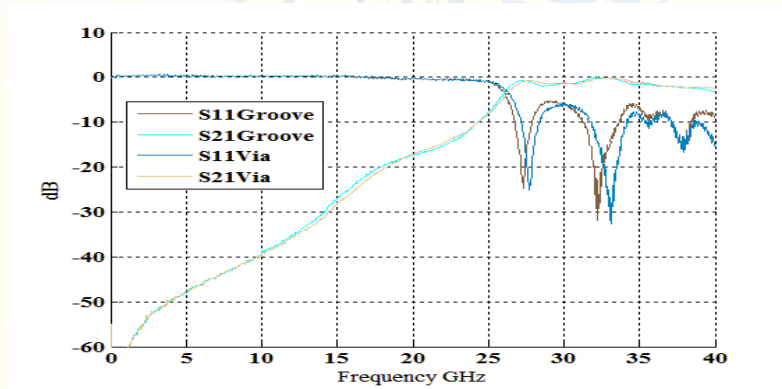


Slide 25

## SIW with solid wall and via posts



Slide 26



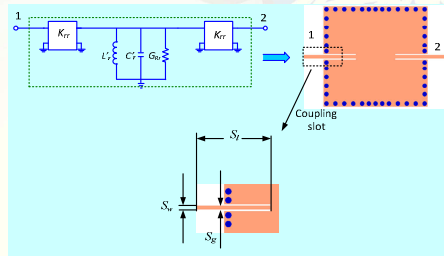
- Both solid walled (groove based) and via post SIW can achieve similar performance

Slide 27

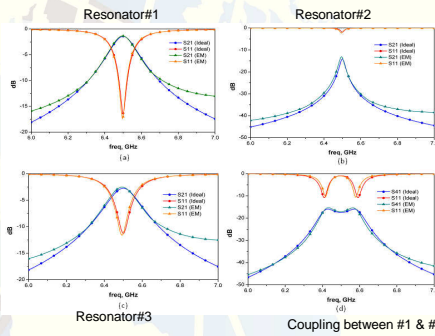
## Further Developments

- Novel filter topologies
- SIW / Antenna integration
- Higher frequencies
- Novel reconfigurable systems

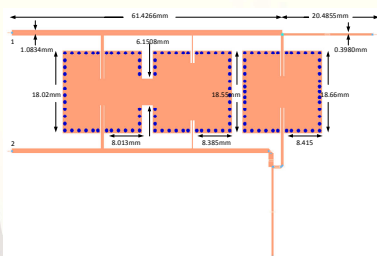
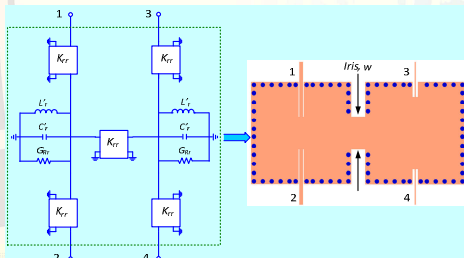
## SIW Resonator



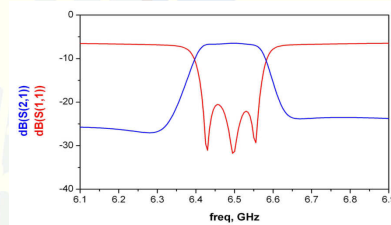
## Ideal vs EM



## Inter-Resonator Coupling

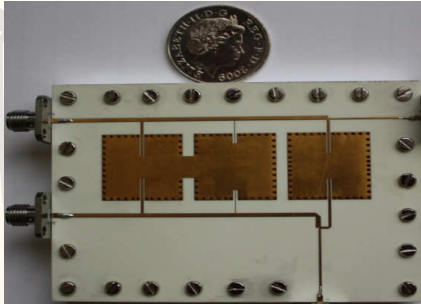


Layout

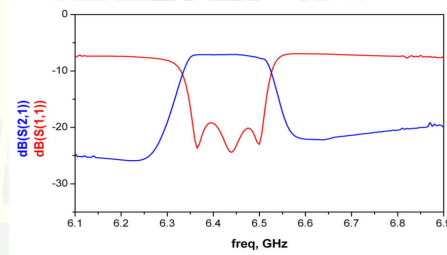


Simulated response

# Results

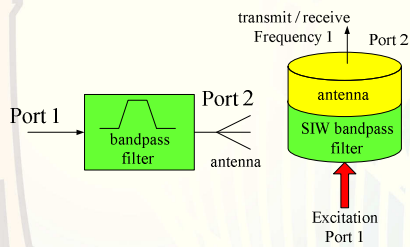


Photograph of the fabricated filter

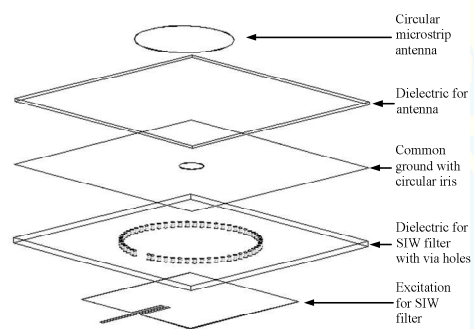


Measured response

# INTEGRATED MICROWAVE FILTER AND ANTENNA



Block diagram

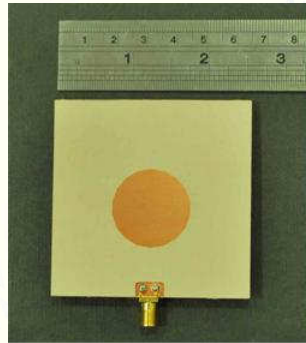


Exploded view

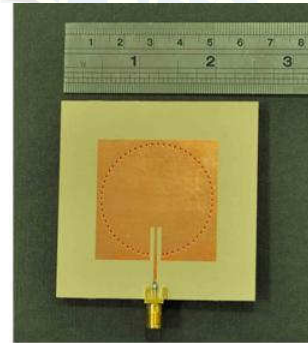


## PHOTOGRAPH OF FABRICATED INTEGRATED SIW FILTER AND MICROSTRIP ANTENNA

Fabricated  
on Rogers  
Duroid  
6010 of  
 $\epsilon_r=10.2$

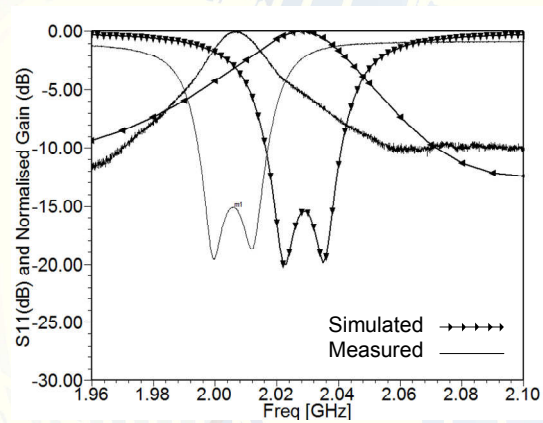


Top View



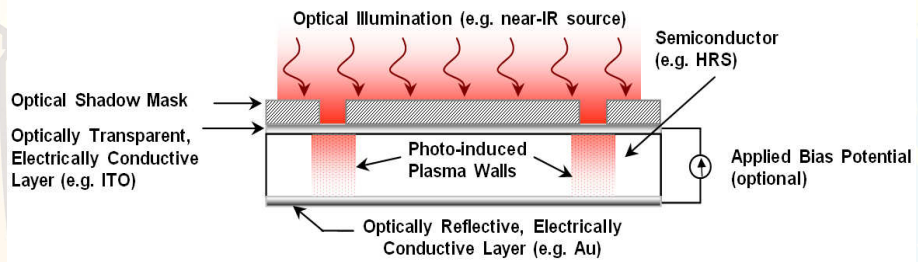
Side View

## SIMULATED AND MEASURED RESULTS



# The RETINA concept

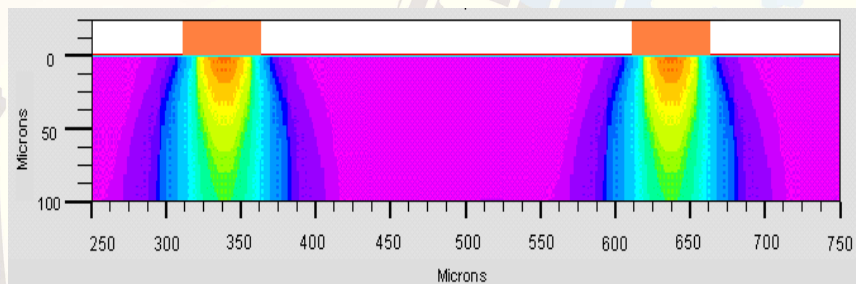
REconfigurable Terahertz INtegrated Architecture (RETINA)



Basic RETINA concept is based on creating virtual side walls using optical illumination and the photoconductivity effect

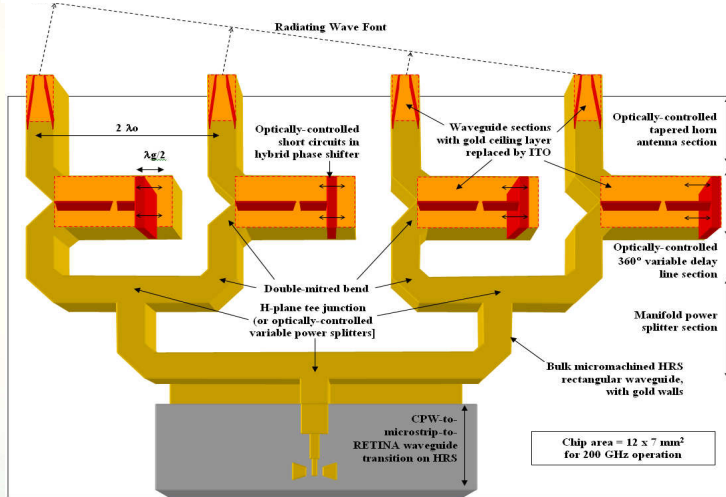
Y. Zhou and S. Lucyszyn, "Modelling of reconfigurable terahertz integrated architecture (RETINA) SIW structures", EM Academy's PIER Journal, vol. 105, pp. 71-92, Jun. 2010

## Silvaco™ TCAD simulations: 2D Luminous



Beam Width = 50  $\mu\text{m}$   
 Wafer Thickness = 100  $\mu\text{m}$   
 Optical Incident Power Range: 10-100  $\text{W}/\text{cm}^2$

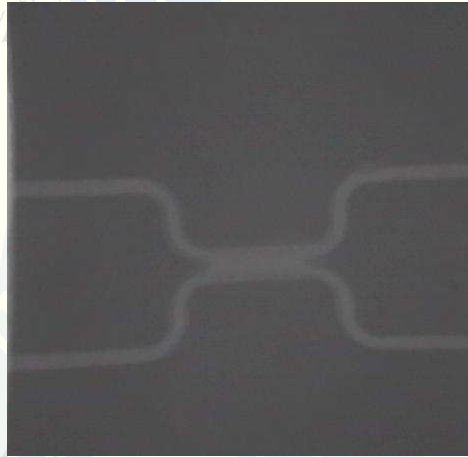
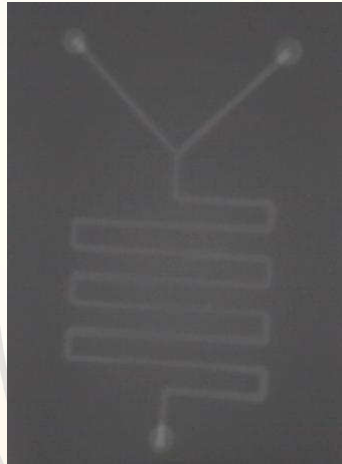
### Scanning phased Array Antenna Concept at 200 GHz



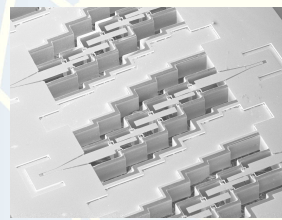
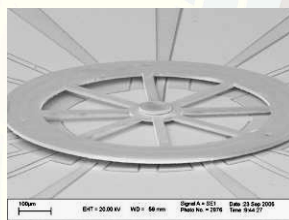
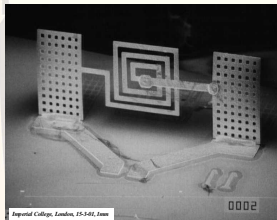
### Loss Comparison with Various SIW Technologies

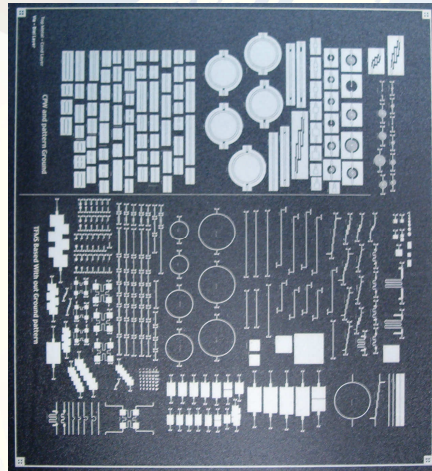
Technology	Frequency (GHz)	Insertion loss (dB/mm)	Conductor loss scaling to 300 GHz (dB/mm)
Alumina SIW	50	0.03	0.07
Ceramic (HT1000) SIW	60	0.20	0.45
Ceramic (QM44F) SIW	74	0.70	1.41
Polyimide (Kapton HN) SIW	79	0.17	0.33
Photoimageable Dielectric HD1000-filled MPRWG	83	1.2	2.3
Air-filled MPRWG	100	0.01	0.017
Polyimide-filled MPRWG	105	8.98	15.18
Air-filled MPRWG	400	0.086	0.074
RETINA (simulated)	300	3.88	3.88

## LTCC Microfluidic Channels



## Previous Imperial-Leeds collaboration in RF MEMS & Micromachined Components





## Collaboration with Mechanical Engineering on Large Area Screen Printing

## Conclusions

**Ceramic technologies are highly suited to the realisation of SIW filters and circuits**

**To go significantly beyond 100 GHz requires research into improved materials and fabrication techniques**

**In LTCC, a wide range of microfluidic and mechanical components can be integrated to form a truly multifunctional system-on-substrate**

**A major challenge for the next few years is to study the feasibility of realising screen-printed RF MEMS integrated with SIWs to make tuneable filters**

**Addressing these challenges can lead to highly novel large-area SIW-based systems**

## Acknowledgments

This work is supported by the  
Science and Engineering Research Council  
and by the  
Innovative Manufacturing Research Centre (ImRC)  
based at Loughborough University.